

**Satellite Workshop of XXXIV International Conference on
Phenomena in Ionized Gases (XXXIV ICPIG) &
10th International Conference on Reactive Plasmas (ICRP-10)**

Challenges in simulation of low-temperature plasma and its applications



**Sapporo Education and Culture Hall, Sapporo,
Hokkaido, Japan**

July 14, 2019

Challenges in simulation of low-temperature plasma and its applications

13:55 - 14:00 Welcome Address, **Fumiyoshi Tochikubo**, Tokyo Metropolitan University, Japan

Chair: Satoshi Hamaguchi

14:00 - 14:30 **Kallol Bera**, Applied Materials, USA
“Simulation of Plasma Sources for Semiconductor Industry”

14:30 - 15:00 **Peter L. G. Ventzek**, Tokyo Electron America, Inc., USA
“Atomic Precision Modeling and Simulation for Atomic Precision Semiconductor Device Fabrication”

15:00 - 15:30 **Atsushi M. Ito**, National Institute for Fusion Research, Japan
“Multi-hybrid simulation for tungsten nanostructure formation induced by helium plasma”

15:30 - 16:00 **Kristof Bal**, University of Antwerp, Belgium
“New physicochemistry at the plasma–catalyst interface: Insights from atomistic modeling”

Coffee Break (15 min)

Chair: Fumiyoshi Tochikubo

16:15 - 16:45 **WooSeok Kang**, Korea Institute of Machinery and Materials, Korea
“Understanding the packed-bed discharges: a simulation perspective”

16:45 - 17:15 **Natalia Babaeva**, Joint Institute for High Temperatures, Russian Academy of Sciences, Russia
“Challenges in modelling and simulation of plasma-surface interaction: fluid vs hybrid approach”

17:15 - 17:45 **Dingxin Liu**, Xi’an Jiaotong University, China
“Modeling study on the interaction between low-temperature plasmas and water solutions”

17:45 - 18:15 **Hiroyuki Nishida**, Tokyo University of Agriculture and Technology, Japan
“Numerical simulation of plasma actuator aiming for understanding of body force generation”

18:15 - 18:25 Concluding Remarks, **Satoshi Hamaguchi**, Osaka University, Japan

19:00 **Reception at the same building (details will be provided)**

Information

Registration: Included in ICPIG/ICRP registration fee

Presentation: Invitation-only

Venue: Sapporo Education and Culture Hall, Sapporo, Hokkaido, Japan

<http://www.kyobun.org/foreign/english.html>

Access: <http://icpig2019.qe.eng.hokudai.ac.jp/venue.html>



Contact: Fumiyoshi Tochikubo
Tokyo Metropolitan University, Japan
e-mail: tochi@tmu.ac.jp